

## **Bulk Nanofabrication with Single Atomic Plane Precision via Atomic-Level Sculpting of Crystalline Oxides**

### **Disclosure Number**

201503502

### **Technology Summary**

The invention comprises a method of nanofabrication with atomic to nanometer scaled precision through controlled electron beam induced irradiation of amorphous and liquid phase precursor solutions using custom built beam controlled algorithms in scanning transmission electron microscope. Inventors have demonstrated the feasibility of this approach for atomic level sculpting of crystalline oxide materials from a metastable amorphous precursor and the liquid phase patterning of nanocrystals.

### **Inventor**

KALININ, SERGEI V  
Center for Nanophase Matls Sciences

### **Licensing Contact**

COCHRAN III, EUGENE R

UT-Battelle, LLC

Oak Ridge National Laboratory

6196

1 Bethel Valley Road

Oak Ridge, TN 37831

Office Phone: (865) 576-2830

E-Mail: [COCHRANER@ORNL.GOV](mailto:COCHRANER@ORNL.GOV)